

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Heaton, John D.; Spady, Blaine R.

Assignee:

Nanometrics Incorporated

Title:

Metrology/Inspection Positioning System

Serial No.:

09/458,123

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Unknown

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ASSISTANT COMMISSIONER FOR PATENTS Washington, D. C. 20231

## INFORMATION DISCLOSURE STATEMENT **UNDER 37 CFR § 1.97(b)**

Dear Sir:

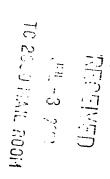
Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

- 1. an admission that the documents are necessarily prior art with respect to the instant invention;
  - 2. a representation that a search has been made, other than as described above; or

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an admission that the information cited herein is, or is considered to be, 3. material to patentability as defined in § 1.56(b).



I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on June 27, 2000.

Attorney for Applicants

Date of Signature

Respectfully submitted,

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